



Cp 2812
10191/2092 *Blw/B*

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Frank FISCHER et al.
Serial No. : 10/066,851
Filing Date : February 4, 2002
For : MICROMECHANICAL COMPONENT AS WELL AS A
METHOD FOR PRODUCING A MICROMECHANICAL
COMPONENT

Examiner : A. Ghyka

Art Unit : 2812

Confirmation No. : 5175

Mail Stop Issue Fee
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

I hereby certify that this correspondence is being deposited with the
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Date: *11/23/04*

Signature: *A. Ghyka*

TRANSMISSION OF REFERENCE AND INFORMATION DISCLOSURE
STATEMENT PURSUANT TO 37 C.F.R. § 1.97(I)

Sir:

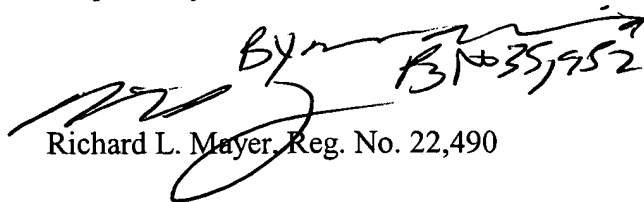

We wish to be made of record the following reference:

Kevin A. Shaw et al, "SCREAM I: A SINGLE-CRYSTAL SILICON PROCESS FOR
MICROELECTROMECHANICAL STRUCTURES, Proceedings of the Workshop on Micro
Electro Mechanical Systems (MEMS), Ft. Lauderdale, FL, Feb. 7-10, 1993; IEEE, US Bd.
Workshop 6, Feb. 1993 (pp. 155-160).

It is respectfully requested that this reference (copy enclosed) be placed in the Patent
Office file for the above-identified patent for interested members of the public in accordance
with 37 C.F.R. § 1.97(I). These references were cited in a counterpart foreign application.

Respectfully submitted,

Dated: 11/23/04

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